

Notice of References Cited		Application/Control No: 09/588,008	Applicant(s)/Patent Under Reexamination YANG ET AL.	
		Examiner Vikki H Trinh	Art Unit 2814	Page 1 of 1

U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-6489199	12-2002	Li et al.	438/253
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
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FOREIGN PATENT DOCUMENTS

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	N					
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Yamagishi et al., Stacked Capacitor DRAM process using photo-CVD Ta?sub 2/O/sub, Electron Devices, IEEE Transaction on, Volume 35 Issue: 12, Dec 1988, p. 2439.
	V	
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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